# **Special Issue**

# State-of-the-Art CMOS and MEMS Devices

# Message from the Guest Editor

CMOS and MEMS devices act as significant roles in the emerging research fields, such as artificial intelligence (AI), 5G communication, and medical electronics. With the continuous development of material science and micro-fabrication processes, high-performance CMOS and MEMS devices are widely investigated and have achieved great progresses. Recently, the rapid development of heterogeneous integration and complex multi-functional systems has put forward higher requirements for CMOS and MEMS Devices, and it is urgent to develop novel CMOS and MEMS devices utilizing advanced materials, techniques, and processes. Thus, in this Special Issue, we invite authors to report the state-of-the-art designs, modeling, fabrication, and applications of CMOS and MEMS devices. The potential topics include, but are not limited to the developments of advanced CMOS devices. CMOS integrated circuits, MEMS devices, 3D integration technology, flexible devices, etc.

#### **Guest Editor**

Prof. Dr. Zhiming Chen

School of Information and Electronics, Beijing Institute of Technology, 5 South Zhongguancun Street, Haidian District, Beijing 100081, China

## Deadline for manuscript submissions

closed (31 December 2023)



# **Micromachines**

an Open Access Journal by MDPI

Impact Factor 3.0 CiteScore 6.0 Indexed in PubMed



mdpi.com/si/122164

Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

mdpi.com/journal/ micromachines





an Open Access Journal by MDPI

Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed



# **About the Journal**

# Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

#### Editor-in-Chief

Prof. Dr. Ai-Qun Liu

Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China

#### **Author Benefits**

## **High Visibility:**

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

## **Journal Rank:**

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

### **Rapid Publication:**

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.2 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the first half of 2025).

